Ensure Chip Performance and Reliability in Clean Environments

Ideal for critical semiconductor applications, Emerson fluid control and pneumatic components and systems ensure high process purity and precision with minimal media contamination in cleanrooms — boosting your throughput and optimizing your fabrication yield rates.

• Emerson fluid control and pneumatic products offer high degrees of performance and dependability, boosting the overall reliability of the chip-making process.

• Products deliver superior performance even in the presence of specialty gases, reducing your maintenance needs and minimizing production downtime.

• Equipped with IIoT capabilities, these products enable temperature, flow, pressure and position control with greater precision and energy efficiency.
## Emerson’s Solutions Offerings

### AMHS

- **Stocker**
- **Contaminants Prevention — N₂ Purging Stations**

### OHT Track

- **Contaminants Prevention**
- **N₂ Purging Station**

### Semiconductor Equipment

- **Asco**
  - **Atmospheric to Vacuum Transfer Module**
  - **Wafer Transfer Module**

- **Asco**
  - **Central Chemical Supply System**

- **Asco**
  - **Abatement Services**

- **Asco**
  - **Vacuum Services**

- **Asco Aventics**
  - **Process Water Treatment**

- **Asco Aventics**
  - **N₂ Purging Loadport**

### Facilities

- **Valve Manifold**

### Typical set up in semiconductor wafer fabrication plant

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For more information:
www.Emerson.com/Semiconductor